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ATTENTION: BOX AFTER FINAL
RESPONSE UNDER 37 C.F.R. § 1.116
EXPEDITED PROCEDURE REQUESTED
EXAMINING GROUP 1762

PATENT
Customer No. 22,852
Attorney Docket No. 08038.0019-00000

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

ok to enter MTP 3/3/03

In re Application of:)
)
H. AMANO) Group Art Unit: 1762
)
Application No.: 09/657,050) Examiner: M. L. Padgett
)
Filed: September 7, 2000)
)
For: Device and Method for Plasma)
Processing)

Assistant Commissioner for Patents
Washington, DC 20231

Sir:

AMENDMENT AFTER FINAL

In reply to the Final Office Action of November 12, 2002, and pursuant to
37 C.F.R. § 1.116, Applicant requests that this application be amended as follows:

IN THE CLAIMS:

Please cancel claim 9.

Please amend claims 1 and 8 as follows:

1. (Twice Amended) A plasma processing apparatus comprising:
a plurality of plasma processing units, each having a vacuum processing
chamber including a mounting stage for mounting a substrate with a fixed reference
point and a wave guide bent at an angle for introducing high frequency waves into said

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